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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

JAMES BROCK STIRTON

Serial No.: 09/824,156

Filed: April 2, 2001

For: METHOD OF MEASURING
IMPLANT PROFILES USING
SCATTEROMETRIC TECHNIQUES

Group Art Unit: 2877

Examiner: Juan D. Valentin


Atty. Dkt. No.: 2000.071000/TT4354

Customer No.: 23720

RESPONSE TO OFFICE ACTION DATED APRIL 27, 2004

Commissioner for Patents
P.O. Box 1450
Washington, DC 20231-1450

Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:	
June 22, 2004 Date	 Signature

This paper is submitted in response to the Office Action dated April 27, 2004 for which the three-month date for response is July 27, 2004.

No fee is believed to be due in connection with the present paper. However, should any fees be required, the Director is authorized to deduct any fees required under 37 C.F.R. §§ 1.16 to 1.21 from the Advanced Micro Devices, Inc. Deposit Account No. 01-0365/TT4354. In the event the monies in that account are insufficient, the Director is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.071000.

Reconsideration of the application in view of the following amendments and remarks is respectfully requested.